



MODEL 1020

Plasma Cleaner

Cleans specimens immediately before they are inserted into the electron microscope; removes existing carbonaceous debris from the specimen and prevents contamination from occurring during imaging and analysis.

Model 1020 Plasma Cleaner specifications

Plasma system

High frequency (13.56 MHz) oscillating field system coupled to a quartz and stainless steel plasma chamber

Ion energies less than 12 eV

Compatible with TEM specimen holders for transmission electron microscopes manufactured by:

- FEI Company/Philips Electron Optics
- Hitachi High Technologies America Inc.
- JEOL Ltd.
- Carl Zeiss Microscopy/LEO Electron Microscopes
- Topcon Corp.

Vacuum system

Oil-free turbomolecular drag pump and a multistage diaphragm pump

Ultimate vacuum of 1×10^{-7} mbar

Gas

25% oxygen and 75% argon

Nominal 103 kPa [15 psi] delivery pressure

Flow rate is factory set and can be adjusted via a potentiometer located on the service panel

Dimensions

59 cm [23.2 in.] width x 52 cm [20.4 in.] height x 59 cm [23.2 in.] depth

Weight

60.6 kg [133.5 lb.]

User interface

Single control panel to initiate vacuum, plasma, and timer

Process timer for automatic termination

Service panel is easily accessible

Power requirements

100/120/220/240 V AC, 50/60 Hz, 660 W

MODEL 1020 Plasma Cleaner

Model 1020 Plasma Cleaner specifications

Warranty

One year



E.A. Fischione Instruments, Inc.
9003 Corporate Circle
Export, PA 15632 USA
Tel: +1 724.325.5444
Fax: +1 724.325.5443
info@fischione.com
www.fischione.com

©2025 E.A. Fischione Instruments, Inc. All rights reserved.
Document Number SP1020 Revision 02 05/2025